



*Engineering Research Center (ERC)  
TeleSeminar, May 26, 2005*

**Novel Subatmospheric  
Pressure Gas Sources For  
Ion Implanters**



# Novel Subatmospheric Pressure Gas Sources For Ion Implanters

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*2005*

# Sub-atmospheric Gas Delivery Options – SAGS recognized in US Fire Codes for increased Safety



Jan. 6, 2005

## Gas adsorbed on a solid

- Gas is adsorbed onto a solid. It is able to be withdrawn when a vacuum (negative pressure relative to the surroundings) is applied to the cylinder

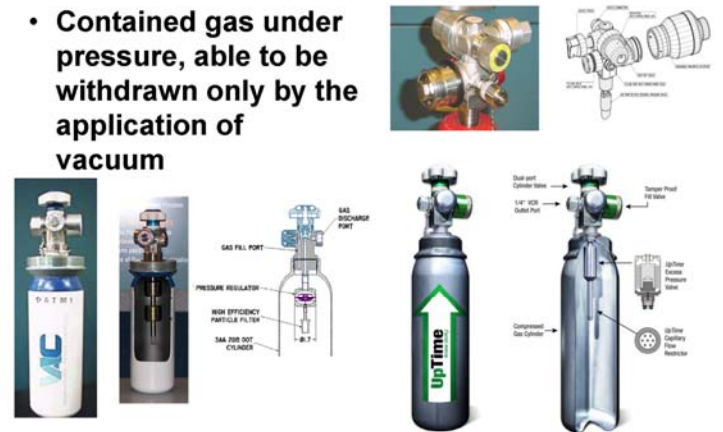


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## Mechanical

- Contained gas under pressure, able to be withdrawn only by the application of vacuum



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## Gas complexed with a liquid

- Gas is complexed (chemically bound) with a liquid. It is only able to be withdrawn by the application of vacuum. The system is analogous to one where gas is adsorbed onto a solid.



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## Gas Generator

- Generates gas to be delivered under vacuum on demand using an electric current.



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# Introducing GASGUARD<sup>®</sup> Sub-Atmospheric Systems (SAS)

- **Program Goal: Develop alternate Ion Implant gas feed systems which meet or exceed current delivery methods and safety to provide customers with sourcing options**
- **GASGUARD<sup>®</sup> SAS - Complexed Gas Technology (CGT)**
  - Ion Implant Grade  $\text{PH}_3$ ,  $\text{BF}_3$ , and  $^{11}\text{BF}_3$
  - Initial Ion Implant Grade  $\text{PH}_3$  beta test successfully started on an Axcelis NV High Energy ion implanter
  - Customers actively qualifying this technology
- **GASGUARD<sup>®</sup> SAS - Generated Gas Technology (GGT)**
  - Ion Implant Grade  $\text{AsH}_3$  has been successfully tested on an Applied Materials 9500 ion implanter for over 1 year
  - Customers actively qualifying this technology

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# GASGUARD<sup>®</sup> Sub-Atmospheric Systems (SAS) - Complexed Gas Technology

- **Gas is complexed (chemically bound) with a liquid. It is only able to be withdrawn by the application of vacuum. The system is analogous to one where gas is adsorbed onto a solid.**
- **Plug and Play for existing sub-atmospheric gas supply systems**

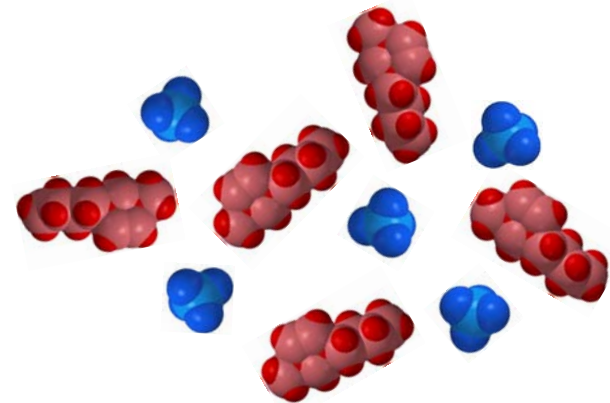
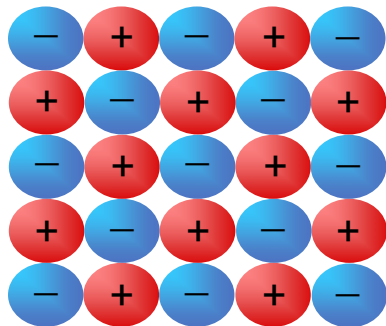




# Complexed Gas Technology Unique Properties

Uses New Field of **Room Temperature IONIC LIQUIDS**

Pending US Patent, Publ.No.US# 2004/0206241 & Patents Pending



Like a conventional  
Salt (e.g. NaCl)...

- No measurable vapor pressure
- Non-flammable
- Chemically and thermally stable

but with unique  
benefits!

- Customizable gas interaction
- Wide liquid temperature range
- Rapid gas and heat transport



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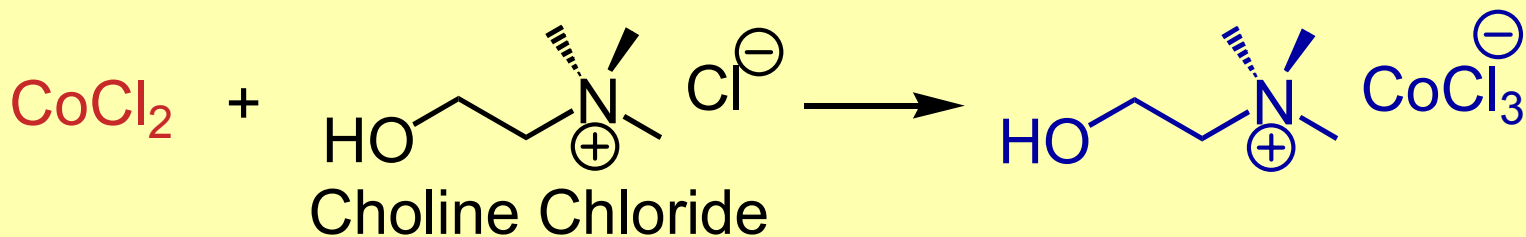
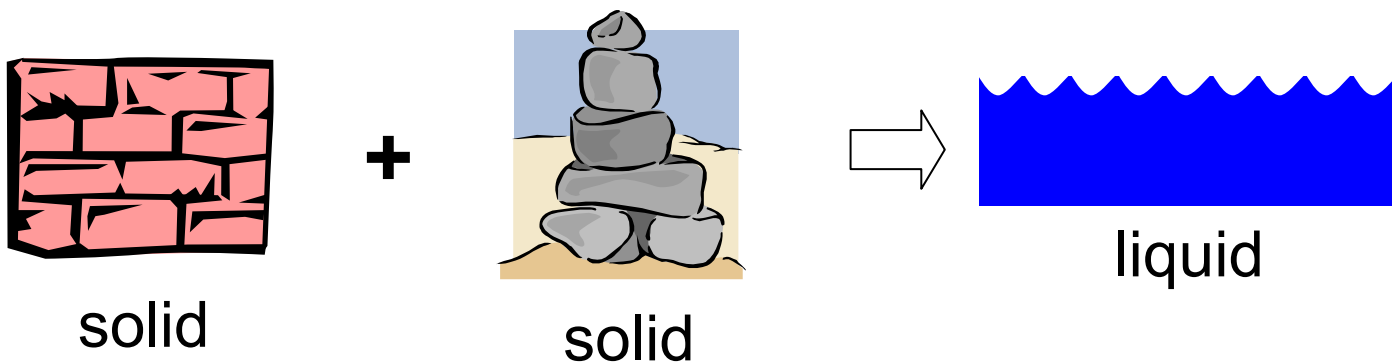
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# Ionic liquids are a new and expanding technology

- **A new class of environmentally friendly solvents**
- **Exponential growth in research since late 1990s**
- **Recyclable "Green" solvents with essentially zero vapor pressure**
- **Limitless number of potential ion combinations**
- **Used as a solvent in chiral synthesis of pharmaceutical and fine chemicals**



# Typical example of an ionic liquid







# Complexed Gas Technology Safety Design Features

- **Intrinsic safety of sub-atmospheric pressure**
  - Passive system, no moving parts
  - Pressure <650 torr at 25 °C
- **MAWP = 2015 psig**
  - > purge gases
- **Membrane eliminates liquid passage**
- **Ionic liquid adds no other hazards**
  - Non-flammable
  - Not-reactive with other gases
  - No measurable vapor pressure
- **Complies to SEMI S-2 and SEMI S-10 standards**

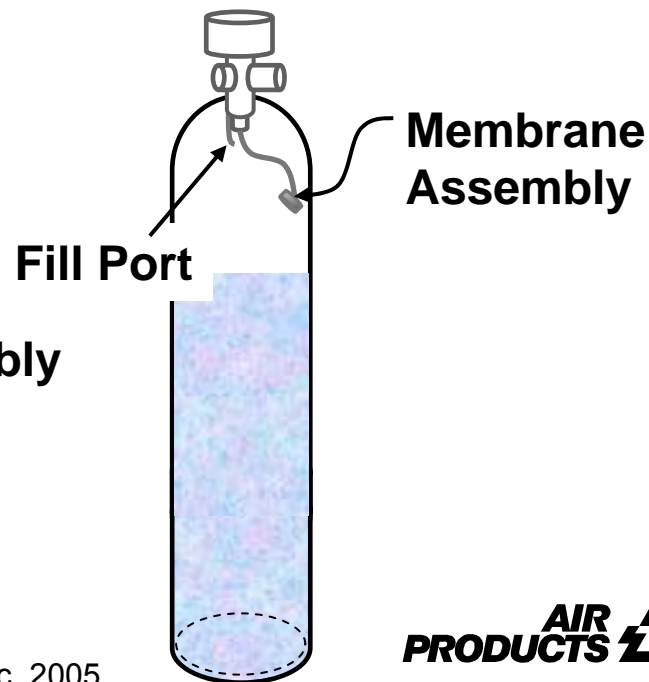
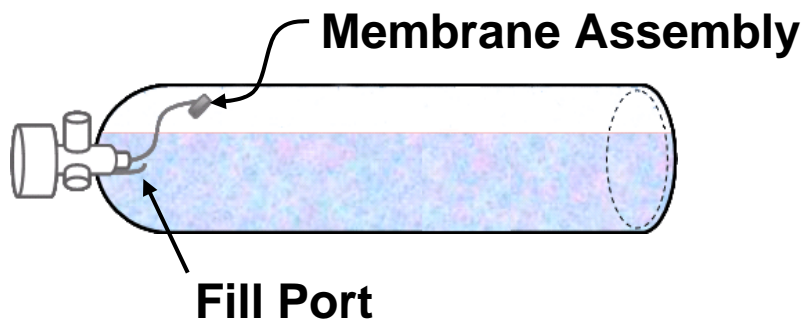
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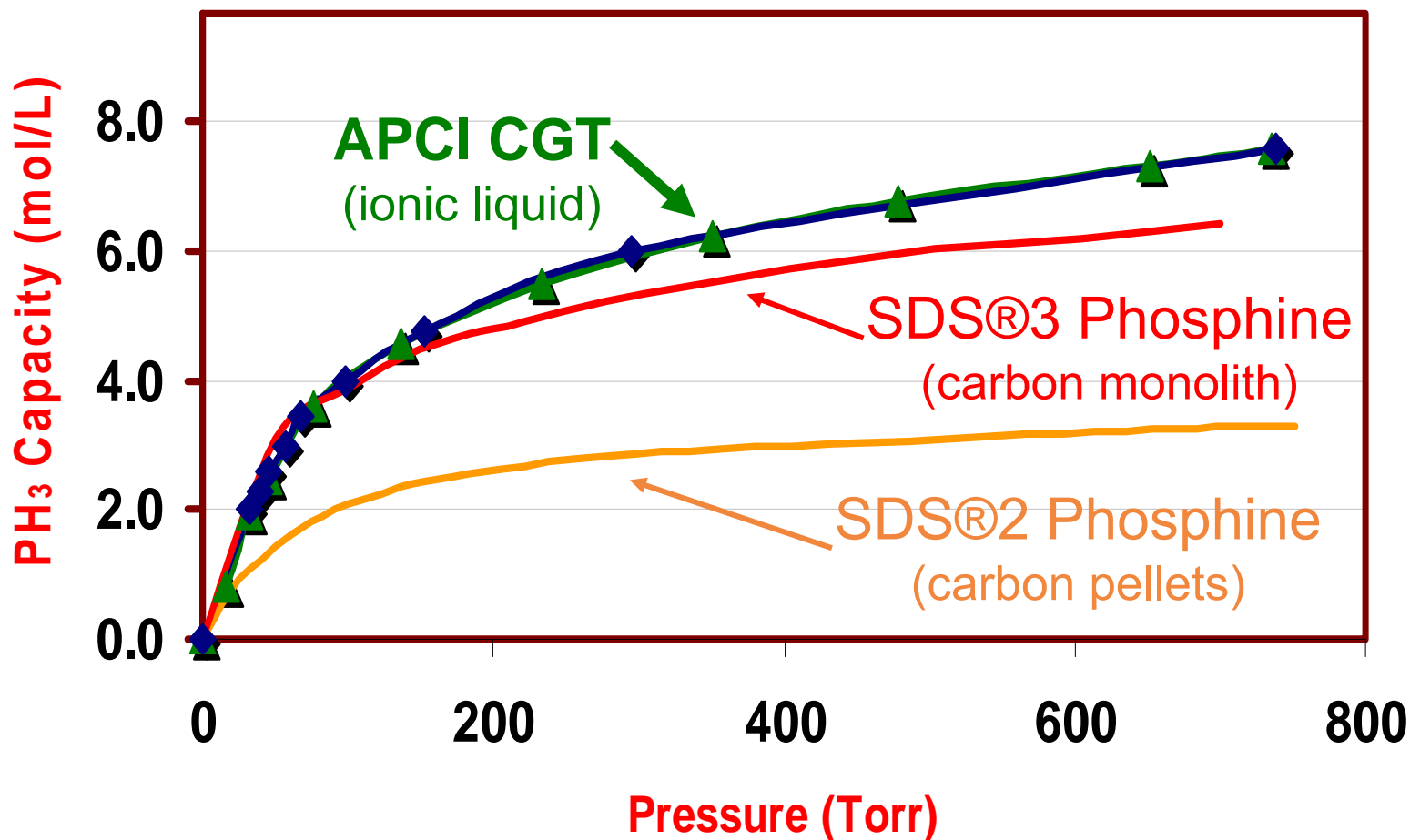


# Complexed Gas Technology Unique Mechanical Design

- **Only desired gas is delivered**
  - A liquid separator prevents reactive ionic liquid from escaping, submerged or entrained droplets
  - Short, curved dip tube
  - Works with vertical or horizontal orientation



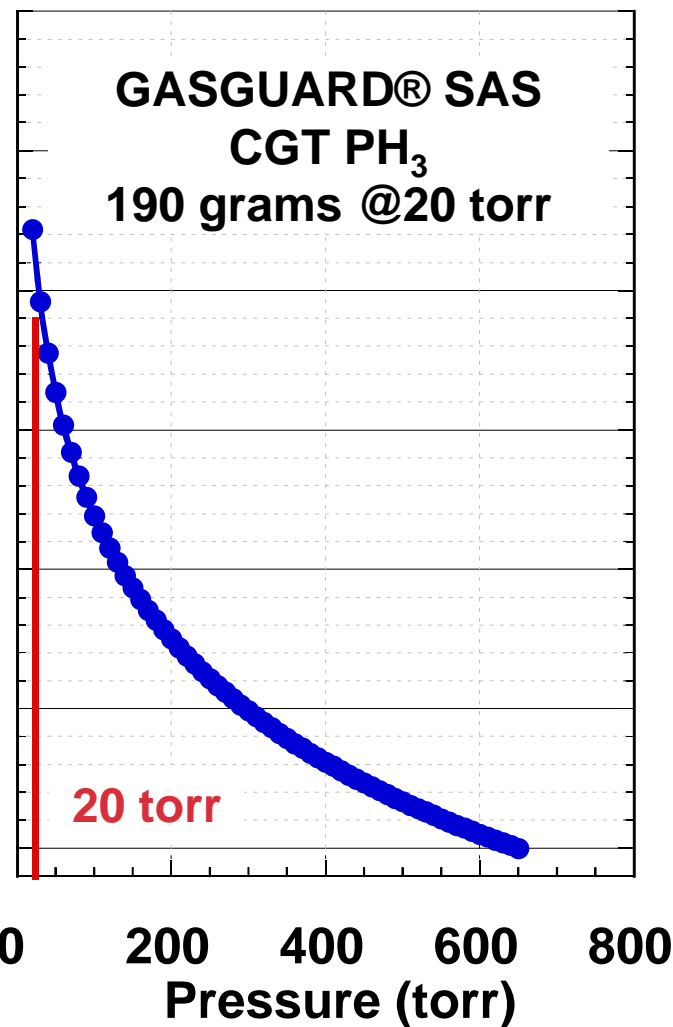
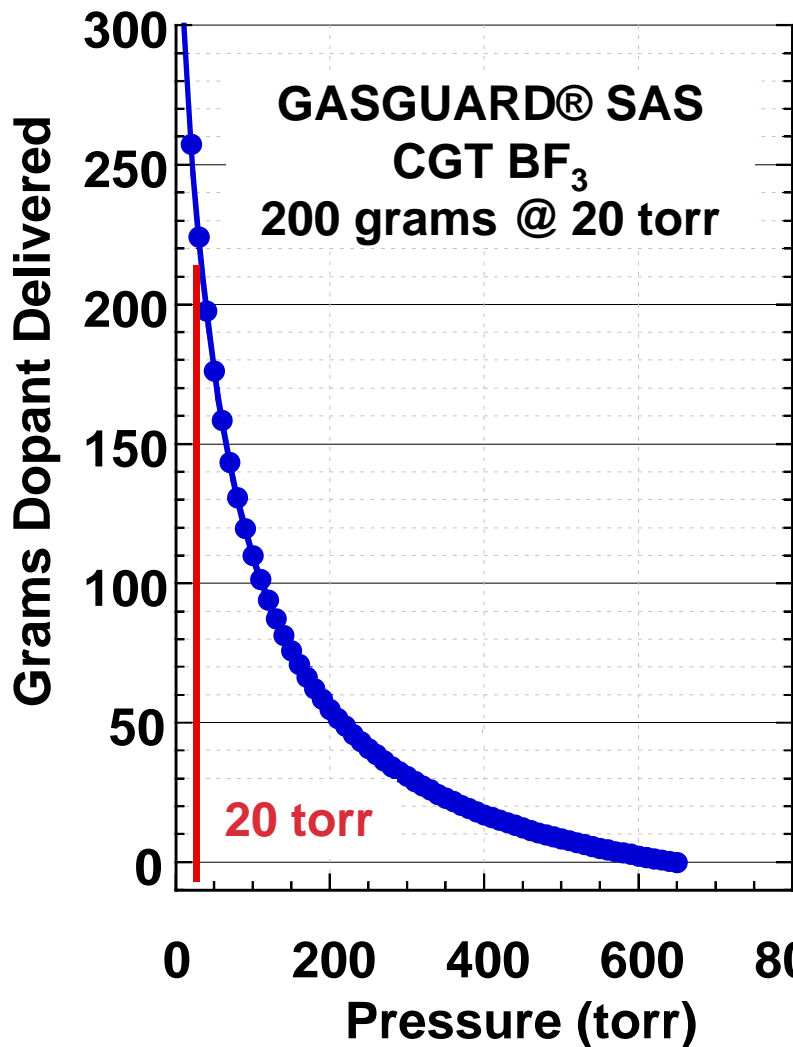
# Complexed Gas Technology PH<sub>3</sub> Equilibrium Capacity



\*SDS®2 Phosphine and SDS®2 Phosphine are registered trademarks of Matheson Tri-Gas and ATMI. Capacity data for SDS®2 Phosphine and SDS®2 Phosphine are from US Pat. No. 5,518,528 and US Pat. No. 6,743,278B1.

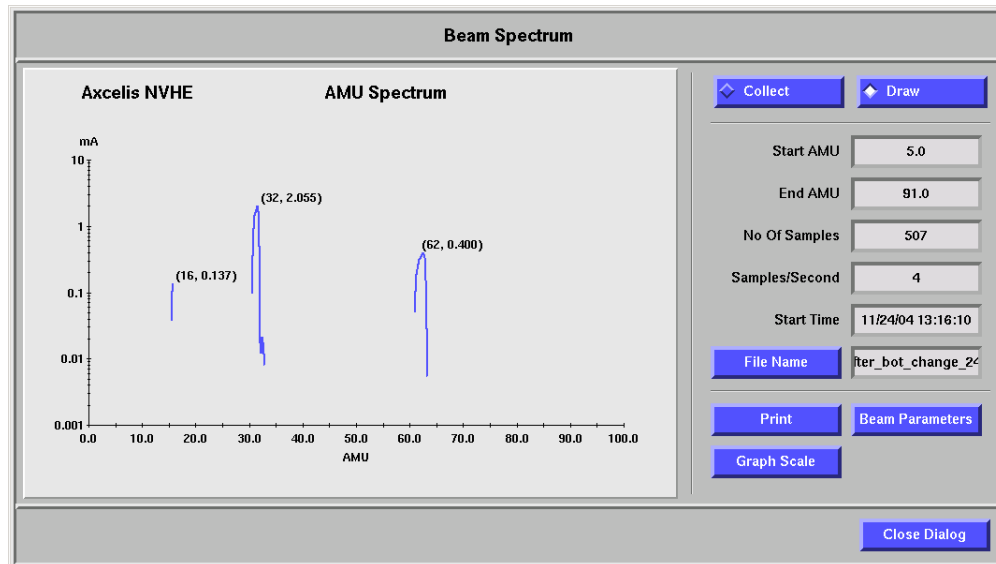


# Complexed Gas Capacity profiles for an X2S - 2.2 liter cylinder





# Complexed Gas Performance Validated on an Axcelis NV High Energy Ion Implanter



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Contaminant	GASGUARD® SAS Phosphine	SDS®2 Phosphine Control
Fe	$<1.0 \times 10^{10} \text{ cm}^{-2}$	$<1.0 \times 10^{10} \text{ cm}^{-2}$
Cu	$<1.5 \times 10^{10} \text{ cm}^{-2}$	$<1.5 \times 10^{10} \text{ cm}^{-2}$
Ni	$<1.0 \times 10^{10} \text{ cm}^{-2}$	$<1.0 \times 10^{10} \text{ cm}^{-2}$
Cr	$<2.0 \times 10^{10} \text{ cm}^{-2}$	$<2.0 \times 10^{10} \text{ cm}^{-2}$
Na	$3.6 \times 10^{10} \text{ cm}^{-2}$	$3.2 \times 10^{10} \text{ cm}^{-2}$
Zn	$0.5 \times 10^{10} \text{ cm}^{-2}$	$5.4 \times 10^{10} \text{ cm}^{-2}$
Ca	$<2.0 \times 10^{10} \text{ cm}^{-2}$	$10.5 \times 10^{10} \text{ cm}^{-2}$
Al	$<1.5 \times 10^{10} \text{ cm}^{-2}$	$9.9 \times 10^{10} \text{ cm}^{-2}$
Fe	$0.5 \times 10^{10} \text{ cm}^{-3}$	$1.0 \times 10^{10} \text{ cm}^{-3}$
Diffusion length	472 $\mu$	430 $\mu$

**VPD-ICP-AAS  
Vapor Phase  
Decomposition  
Inductively  
Plasma Coupled  
Atomic  
Absorption  
Spectrometry  
data**

**SPV  
Surface Photo  
Voltage**

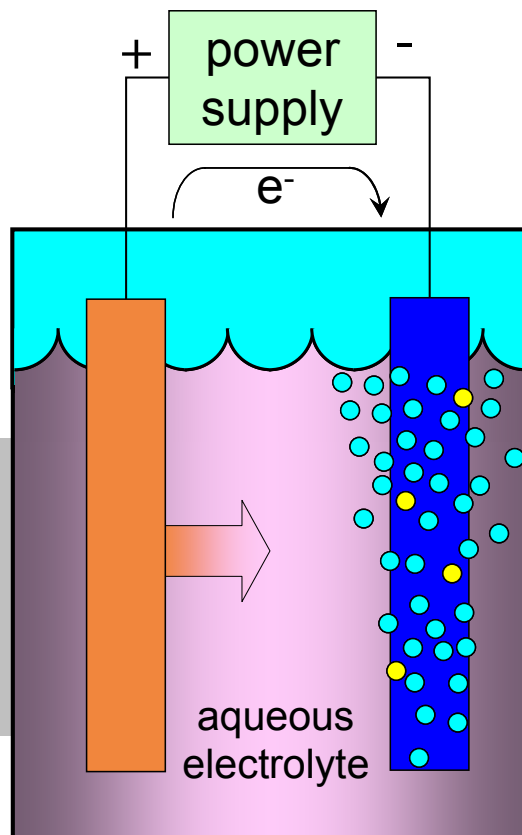


# GASGUARD<sup>®</sup> Sub-Atmospheric Systems (SAS) - Generated Gas Technology

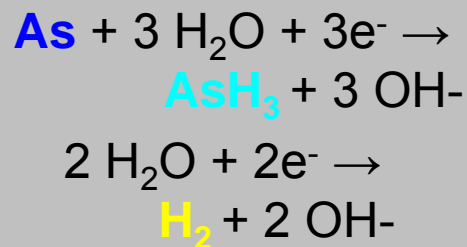
- Generates gas under vacuum on-demand using an electric current
- US Patent No. 5,158,656 and Patents Pending



Anode =  
sacrificial  
metal



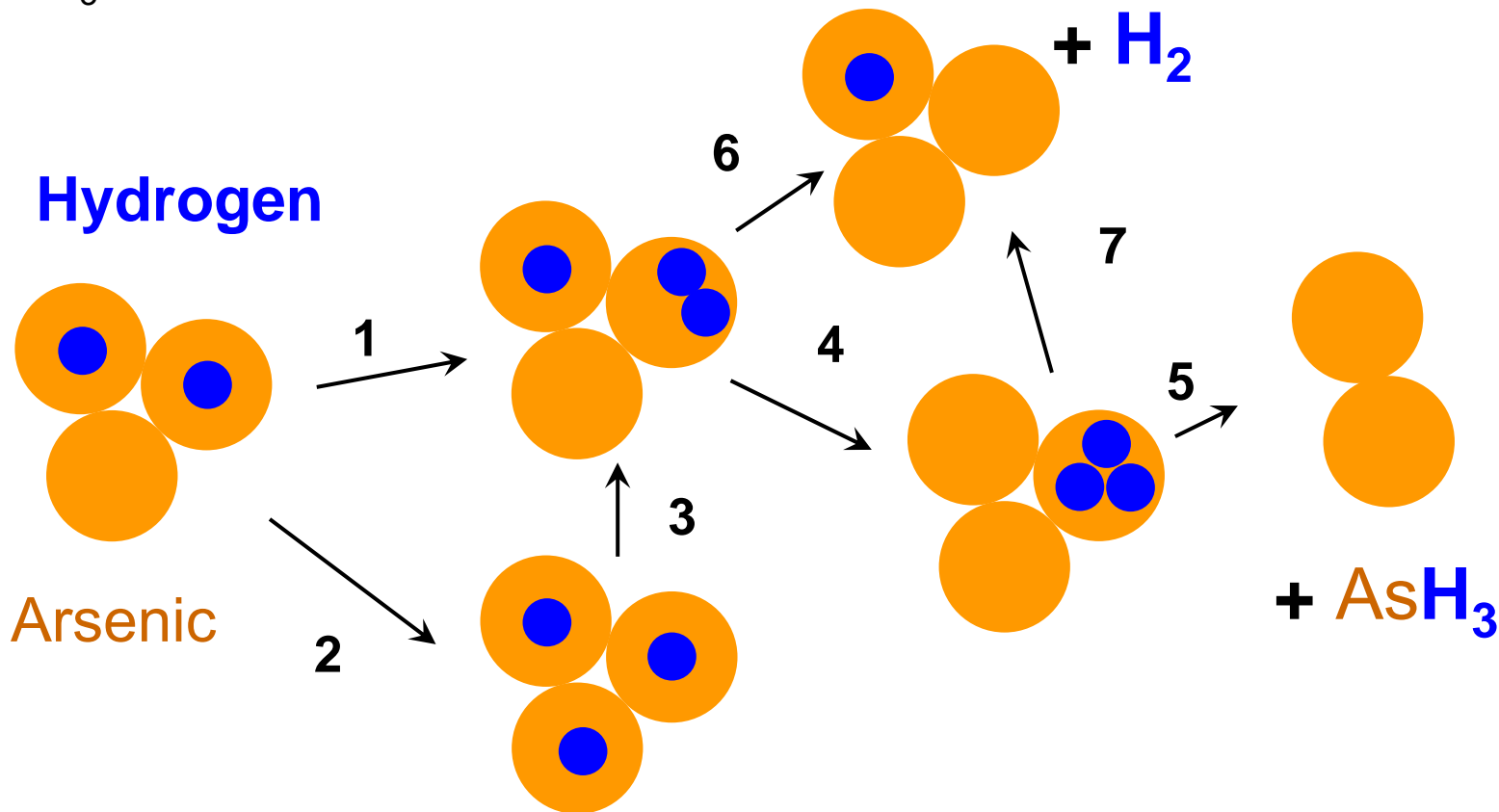
Cathode =  
arsenic  
containing  
electrode





# Arsenic hydride disproportionation is key to high arsine yields

$H_2$  is the thermodynamically favored but  $AsH_3$  can be made >90% if kinetics are controlled



J. Elect. Soc. Vol 107, pg. 348-353 April 1960



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# Generated Gas Technology Intrinsic Safety Design features

- **Arsine inventory is minimized**
  - 0 grams during shipping
    - Can be air freighted
    - No  $\text{AsH}_3$  volume restrictions during storage
  - 1 gram  $\text{AsH}_3$  during operation
    - Produced on-demand at a constant 400 torr with rates between 0 and 10 sccm
- **Generator sub-atmospheric during storage and operation**
  - Minimizes exposure and accidental release
  - Subatmospheric at elevated temperatures
  - Subatmospheric in high-elevation Fabs
- **Reduced change-outs: high capacity and robust design**
  - 2 liter generator delivers 660 grams  $\text{AsH}_3$
  - Capacity gauged to avoid early change-out
  - If contaminated with purge gas, generator can be evacuated and restarted with out change-out
  - MAWP = 160 psig > purge gas supply



# 5 levels of instrumented safety

**1 Operating power interface:** Control box tied into available gas box 24VDC supply

- Interfaces with implanter safety systems

**2 Pneumatic interface:** Pneumatic control line from the gas feed valve to control box

- Power off when gas demand stops
- Interfaces with implanter safety systems

**3 Pressure controller:** On generator maintains pressure between 405-410 torr

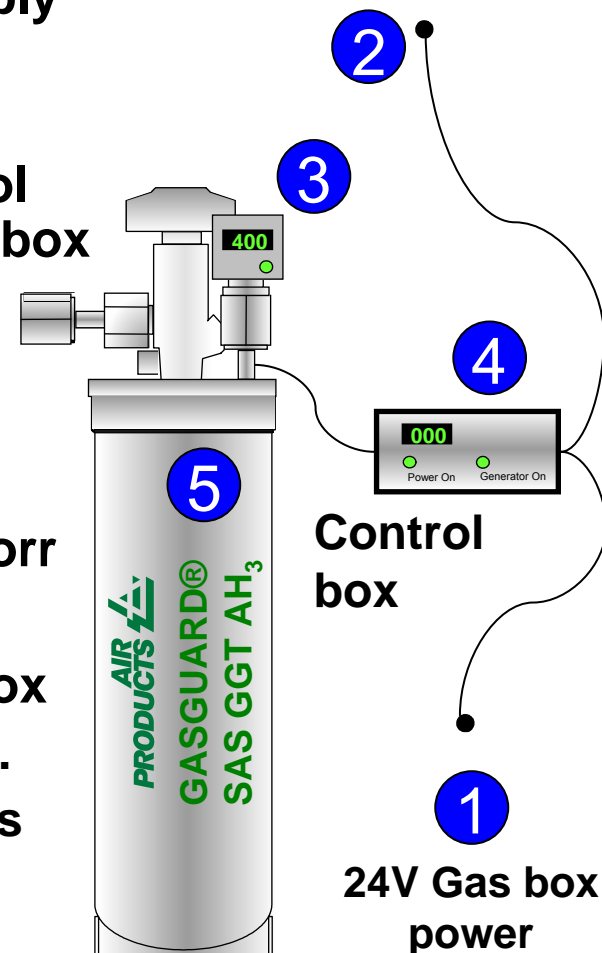
- Power off if  $P > 410$  torr

**4 Watch-dog timer:** Located in control box

- Power off if current is “on”  $>90$  min.
- Typical operation for 2 sccm  $\text{AsH}_3$  is 1-2 min. “on” and 6-12 min. “off”

**5 Over-pressure switch:** Built into generator

- Power off if  $P > 1$  barg





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# Safety Design and Documentation

- **GASGUARD® SAS GGT adheres to the requirements set by the European Pressure Equipment Directive 97/23/EC**
  - **Designed in accordance with SOUND ENGINEERING PRACTICE (ASME BPV code Section VIII, division 1, July 2001 Edition with Addenda; supplemented by PD5500:2003 Amendment 1 ; ASME BPV code case 2211)**
- **Electronics system is CE marked**
- **Complies to SEMI S-2 and SEMI S-10 standards**

# Generator specifications

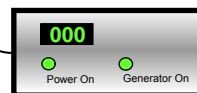
## Generator

size	2.2 liters
diameter	114.5 mm
height to valve	449 mm
valve	Proprietary valve with 1/2" *VCR® Fitting
capacity	660 g AsH <sub>3</sub>
rate	0-10 sccm continuous
AsH <sub>3</sub> mole %	93-95% (make-up H <sub>2</sub> )



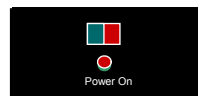
Implant tool  
pneumatic  
"on" signal

Controller



24V Gas box  
power

Optional  
power  
supply



## Controller

location	gas box
size	105 mm x 60 mm x 105 mm
input	18-36 VDC
"on" signal	air >60 psig

## Optional power supply

location	transformer rack
size	105 mm x 60 mm x 125 mm
input	120-220 VAC
output	24 VDC, 2.5 A

\*VCR® Fitting is a registered trademark of the Swagelok Company





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# Generated Gas Technology (GGT) Performance Validated on an Applied Materials 9500 Ion Implanter

- **Operating since February 2004**
- **Reliable service to supply 660 grams  $\text{AsH}_3$**
- **Wafer product quality comparable to other  $\text{AsH}_3$  sources**
  - **Stable beam currents**
  - **Successful at various recipes**
  - **No wafer or tool contamination identified**
- **No change in ion source life or operation**



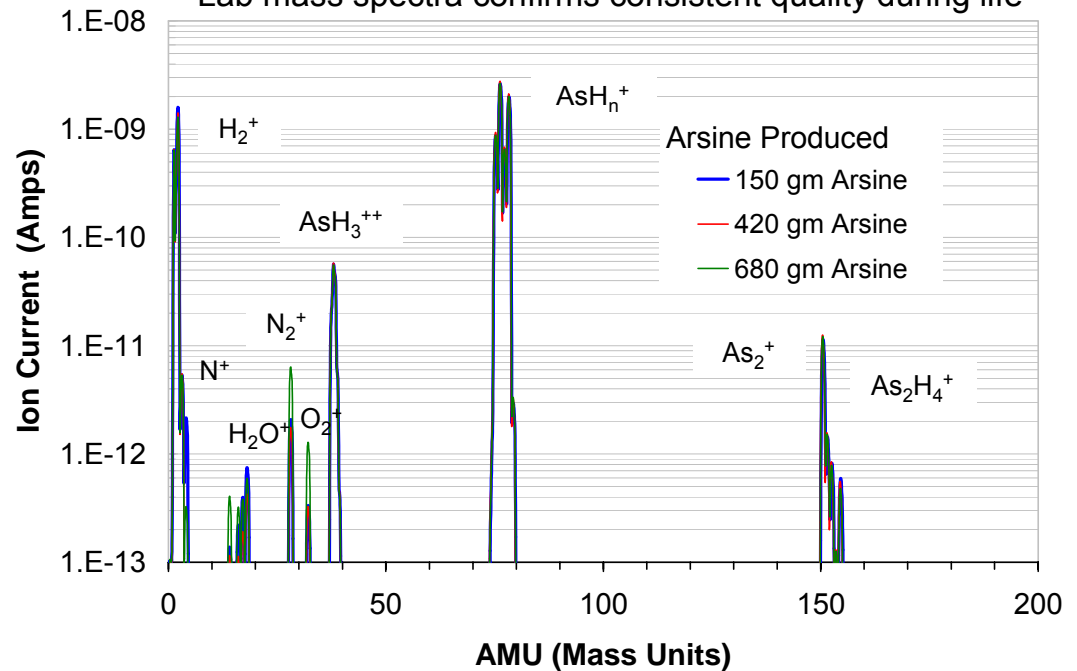


# Comparisons for Generated Gas Performance and Quality

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Lab mass spectra confirms consistent quality during life



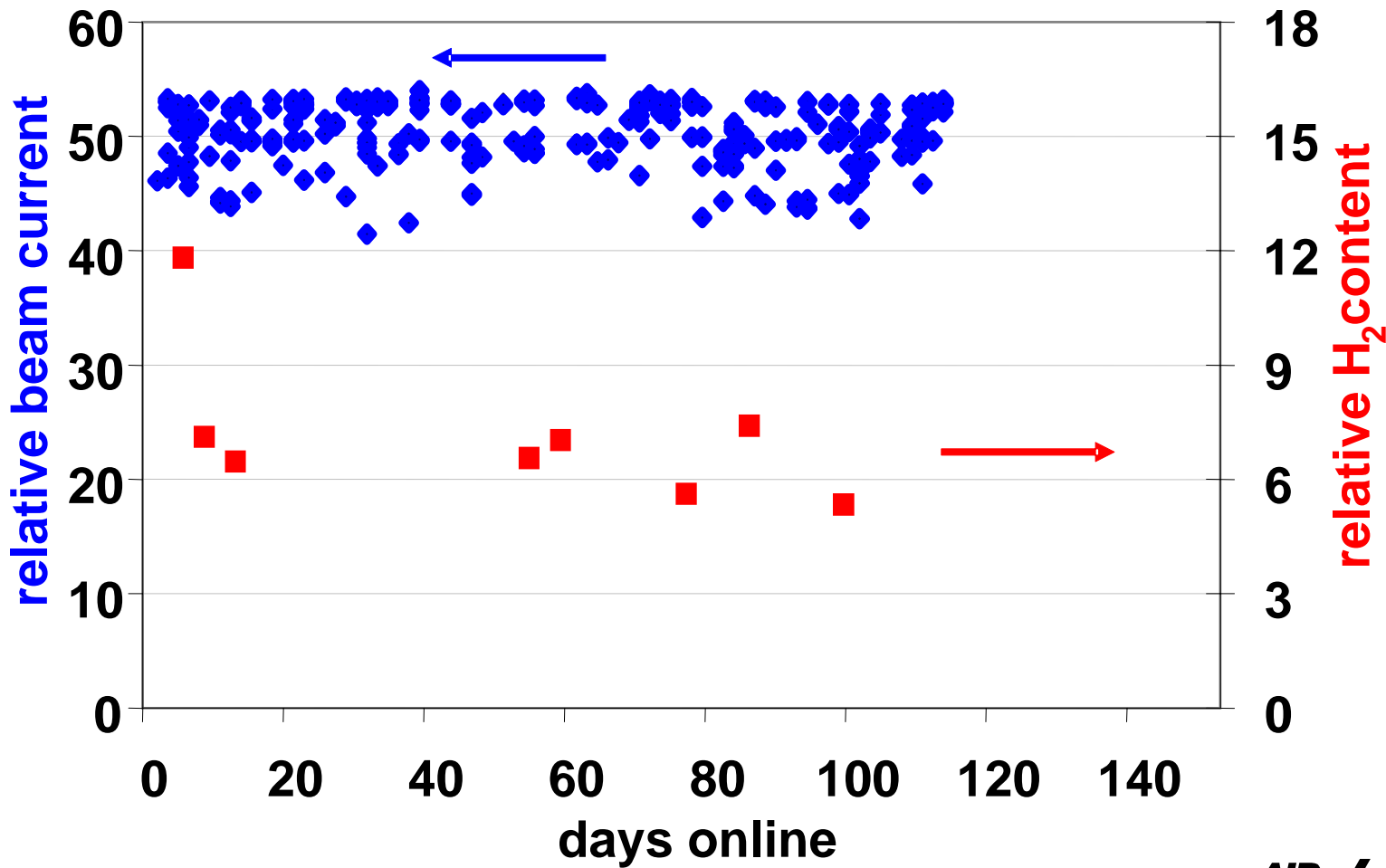
	<b>GASGUARD® SAS AsH<sub>3</sub></b>	<b>SDS®2 AsH<sub>3</sub></b>
<b>Arsine, volume %</b>	<b>&gt; 93%</b>	<b>≥ 99.9995%</b>
<b>Arsine (H<sub>2</sub> free basis) vol%</b>	<b>≥ 99.9995%</b>	<b>NA</b>
<b>Hydrogen, volume%</b>	<b>&lt; 7%</b>	<b>NA</b>
<b>Oxygen, ppmv</b>	<b>&lt;1.0</b>	<b>&lt; 1.0</b>
<b>Nitrogen, ppmv</b>	<b>&lt;2.0</b>	<b>&lt;2.0</b>
<b>Carbon dioxide, ppmv</b>	<b>&lt;0.5</b>	<b>&lt;0.5</b>
<b>Carbon monoxide, ppmv</b>	<b>&lt;0.1</b>	<b>&lt;0.1</b>
<b>Methane, ppmv</b>	<b>&lt;0.1</b>	<b>&lt;0.5</b>
<b>Water , ppmv</b>	<b>&lt;2.0</b>	<b>&lt;2.0</b>

SDS®2 AsH<sub>3</sub> specifications are from Matheson Tri-gas Product Brochure 4/03





Generated  $\text{AsH}_3$  produces stable ion beam currents comparable to other commercial  $\text{AsH}_3$  sources



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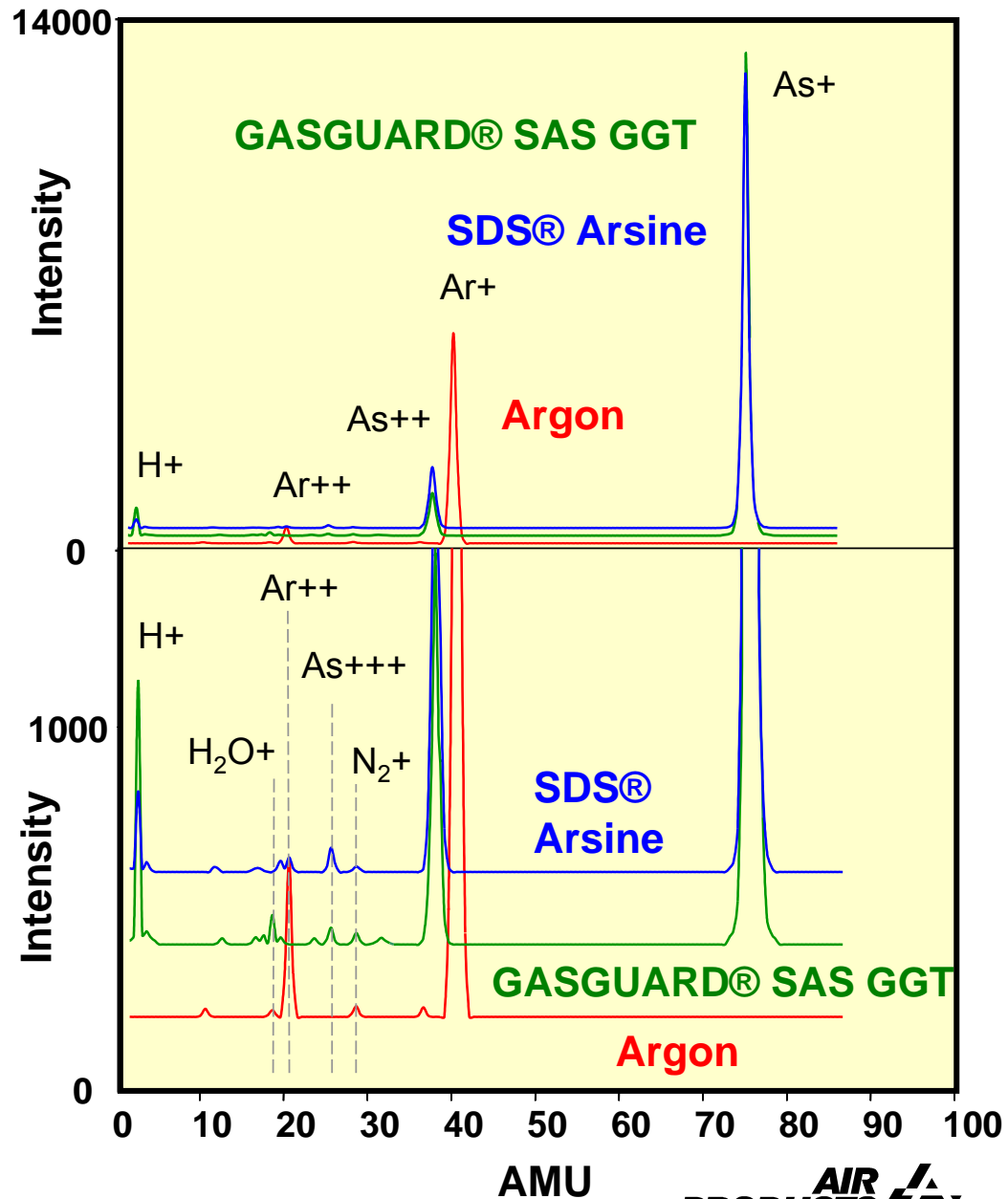
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GGT Arsine  
mass  
spectra on  
an Applied  
Materials  
9500 Ion  
Implanter  
compares  
to SDS®  
Arsine





# Generated Gas Technology Wafer and Particle Quality

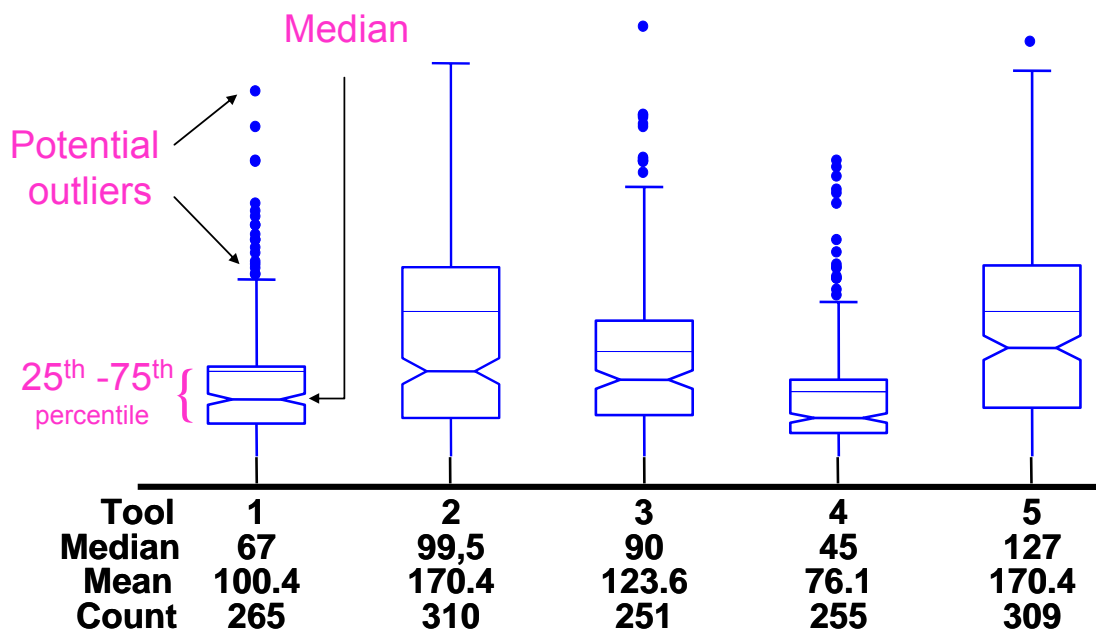
VPD-ICP-MS Vapor Phase Decomposition

Inductively Plasma Coupled Mass Spectrometry data

Values in 1E10 atoms/cm <sup>2</sup>	K	Na	Al	Fe	Cu	Ni	Cr	Zn
GGT Arsine	<0.1	31	54	2.3	1.5	<0.4	0.3	1.4
SDS® Arsine	<0.1	42	160	2.9	2.8	<0.4	0.2	2.4
Reference	<0.1	27	13	1.5	<0.1	<0.4	<0.1	3.3

Tool 1 running with GGT Arsine others on SDS® Arsine

Particle Quality







# GASGUARD<sup>®</sup> Sub-Atmospheric Systems (SAS) - Available Now

- **Complexed Gas Technology:**

- **PH<sub>3</sub>, <sup>11</sup>BF<sub>3</sub>, BF<sub>3</sub> available as Plug and Play replacements for existing sub-atmospheric gas supply systems**
  - **2.2 L size containers**
  - **Horizontal or vertical orientation**
  - **Face-seal VCR<sup>®</sup> Fitting -compatible connections**

- **Generated Gas Technology:**

- **AsH<sub>3</sub> available as replacement for existing sub-atmospheric gas supply systems**
  - **2.2 L size containers**
  - **Vertical orientation**
  - **Face-seal VCR<sup>®</sup> Fitting -compatible connections**
  - **Requires minor modifications for first time electrical installation connections**